

10/06/01  
12/03/01

U.S. UTILITY Patent Application

PATENT NUMBER and  
ISSUE DATE

APPL NUM 10006100	FILING DATE 12/03/2001	CLASS 438	SUBCLASS 345.33	GAU 2812	EXAMINER ZERVIGUN
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\*\*APPLICANTS: Shepherd Robert; Caughran James;

\*\*CONTINUING DATA VERIFIED:

N/A 2/7 8/24/3

\*\* FOREIGN APPLICATIONS VERIFIED:

N/A 2/7 8/24/3

PG-PUB	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>
Foreign priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no		ATTORNEY DOCKET NO
35 USC 119 conditions met <input type="checkbox"/> yes <input type="checkbox"/> no		NOVEP015
Verified and Acknowledged Examiners's initials		
TITLE : Method and apparatus for plasma optimization in wafer processing		

U.S. DEPT. OF COMM./PAT. & TM.-PTO-436L (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Total Claims	Print Claim for O.G.
Assistant Examiner		DRAWING	
		Sheets Drwg.	Figs. Drwg.
Primary Examiner		Print Fig.	
PREPARED FOR ISSUE		Application Examiner	
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